Amendment dated April 14, 2004

Reply to final Office Action dated January 14, 2004

Listing of the Claims:

1. (Currently Amended) An in-plane switching liquid crystal display device comprising:

first and second substrates;

- a gate line arranged in one direction on the first substrate;
- a common line arranged on the first substrate;
- a gate insulation layer on the first substrate;
- a data line on the gate insulation layer;
- a first passivation layer on the gate insulation layer;
- a plurality of common electrodes in contact with [[on]] the first passivation layer;
- a second passivation layer on the first passivation layer, wherein the second passivation layer is an inorganic material;
 - a plurality of pixel electrodes on the second passivation layer; and
 - a liquid crystal layer between the first and second substrates.
- 2. (Currently Amended) The device of claim 1, wherein the common and pixel electrodes are formed of [[the]] a transparent conductive material.
- 3. (Original) The device of claim 2, wherein the transparent conductive material includes at least one of indium tin oxide (ITO) or indium zinc oxide (IZO).
- 4. (Original) The device of claim 1, wherein the gate insulation layer and the second passivation layer are one of Silicon Nitride (SiN_X) and Silicon Oxide (SiO₂).
- 5. (Original) The device of claim 1, wherein the first passivation layer is formed of an organic material.
- 6. (Original) The device of claim 5, wherein the organic material is one of benzocyclobutene (BCB) and acryl.
- 7. (Original) The device of claim 1, wherein the common line is parallel with the gate line and spaced apart from the gate line.
- 8. (Original) The device of claim 1, wherein the data line is perpendicular to the gate line.

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9. (Previously Presented) The device of claim 1, further comprising a thin film transistor at a crossing point of the gate line and the data line.

- 10. (Original) The device of claim 9, wherein the thin film transistor includes a gate electrode, an active layer, and source and drain electrodes.
- 11. (Original) The device of claim 1, wherein the first passivation layer includes a plurality of common line contact holes.
- 12. (Previously Presented) The device of claim 11, wherein each common electrode is electrically connected with the common line through a corresponding common line contact hole.
- 13. (Original) The device of claim 1, wherein the second passivation layer includes a drain contact hole.
- 14. (Original) The device of claim 13, wherein one of the plurality of pixel electrodes is electrically connected with the drain electrode through the drain contact hole.
- 15. (Original) The device of claim 1, wherein each pixel electrode is arranged between the adjacent common electrodes.
- 16. (Currently Amended) A method of fabricating an array substrate for an in-plane switching liquid crystal device, the method comprising:

forming a gate electrode, a gate line and a common line on a substrate with a first metal layer;

forming a gate insulation layer on the substrate;

forming a data line and source and drain electrodes with a second metal layer;

forming a first passivation layer on the gate insulation layer;

forming a plurality of common electrodes <u>in contact with</u> [[on]] the first passivation layer;

forming a second passivation layer on the first passivation layer, wherein the second passivation layer is an inorganic material; and

forming a plurality of pixel electrodes on the second passivation layer.

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17. (Original) The method of claim 16, wherein the step of forming the plurality of common electrodes comprises depositing and patterning a first transparent conductive material.

- 18. (Original) The method of claim 17, wherein the first transparent conductive material is one of indium tin oxide (ITO) and indium zinc oxide (IZO).
- 19. (Original) The method of claim 16, wherein the step of forming the pixel electrodes comprises depositing and patterning a second transparent conductive material.
- 20. (Original) The method of claim 19, wherein the second transparent conductive material is one of indium tin oxide (ITO) and indium zinc oxide (IZO).
- 21. (Original) The method of claim 16, wherein the first passivation layer is an organic material.
- 22. (Original) The method of claim 21, wherein the organic material is one of benzocyclobutene (BCB) and acryl.
- 23. (Original) The method of claim 16, wherein the gate insulation layer and the second passivation layer are one of Silicon Nitride (SiN_X) and Silicon Oxide (SiO₂).
- 24. (Original) The method of claim 16, wherein the first and second metal layer include a material selected from a group consisting of chromium (Cr), aluminum (Al), aluminum alloy (Al alloy), molybdenum (Mo), tantalum (Ta), tungsten (W), antimony (Sb), and an alloy thereof.
- 25. (Original) The method of claim 16, wherein the first passivation layer includes a plurality of common line contact holes.
- 26. (Original) The method of claim 25, wherein each common electrode is electrically connected with the common line through each common line contact hole.
- 27. (Original) The method of claim 16, wherein the second passivation layer includes a drain contact hole.
- 28. (Original) The method of claim 27, wherein one of the plurality of pixel electrodes is electrically connected with the drain electrode through the drain contact hole.

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29. (Original) The method of claim 16, wherein each pixel electrode is arranged between adjacent common electrodes.

30. (Currently Amended) An in-plane switching liquid crystal display device, comprising:

first and second substrates;

gate lines on the first substrate;

data lines perpendicular to the gate lines to form a plurality of pixel regions;

a thin film transistor in each of the pixel regions at a crossing point of the data lines and the gate lines;

a common line on the first substrate in each of the pixel regions, the common line parallel to the gate lines;

- a first insulation layer over the gate lines, the data lines being on the first insulation layer;
- a second insulation layer over the data lines and the common line;
- a plurality of first contact holes through the first and second insulation layers over the common line;
- a plurality of common electrodes <u>in contact with</u> [[on]] the second insulation layer, wherein the common electrodes contact the common line via the first contact holes;
- a third insulation layer on the common electrodes and the second insulation layer, wherein the third insulation layer is an inorganic material;
- a second contact hole through the second and third insulation layers over a drain electrode of the thin film transistor;
 - a plurality of pixel electrodes on the third insulation layer; and
 - a liquid crystal interposed between the first and second substrates.
- 31. (Original) The device of claim 30, wherein the pixel electrodes electrically communicate with one another via a transverse pixel electrode perpendicular to the common electrodes.
- 32. (Original) The device of claim 30, wherein the pixel electrodes and the common electrodes are formed of a transparent conductive material.
- 33. (Original) The device of claim 30, wherein the transparent conductive material is one of indium tin oxide and indium zinc oxide.

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34. (Original) The device of claim 30, wherein the first and third insulation layers are formed of one of Silicon Nitride (SiNx) and Silicon Oxide.

- 35. (Original) The device of claim 30, wherein the second insulation layer is formed of an organic material.
- 36. (Original) The device of claim 35, wherein the organic material is one of benzocyclobutene (BCB) and acryl.